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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/032,219	12/21/2001	Cyprian E. Uzoh	042496/0269264 NT-235	3469
7590 01/15/2004			EXAMI	
Pillsbury Wint	throp LLP		CHEN, KI	N CHAN
Intellectual Property Group 1600 Tysons Boulevard McLean, VA 22102			ART UNIT	PAPER NUMBER
			1765	
		DATE MAILED: 01/15/2004		

Please find below and/or attached an Office communication concerning this application or proceeding.

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•	Application No.	Applicant(s)				
	10/032,219	UZOH ET AL.				
Office Action Summary	Examiner	Art Unit				
	Kin-Chan Chen	1765				
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the	correspondence address				
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply If NO period for reply is specified above, the maximum statutory period w Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b). Status	36(a). In no event, however, may a reply be ti within the statutory minimum of thirty (30) da will apply and will expire SIX (6) MONTHS fron cause the application to become ABANDONI	mely filed ys will be considered timely. n the mailing date of this communication. ED (35 U.S.C. § 133).				
1) Responsive to communication(s) filed on						
2a)⊠ This action is FINAL . 2b)□ This	action is non-final.					
3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.						
Disposition of Claims						
4) ☐ Claim(s) 1-16 is/are pending in the application. 4a) Of the above claim(s) is/are withdrawn from consideration. 5) ☐ Claim(s) is/are allowed. 6) ☐ Claim(s) 1-16 is/are rejected. 7) ☐ Claim(s) is/are objected to. 8) ☐ Claim(s) are subject to restriction and/or election requirement.						
Application Papers						
9) The specification is objected to by the Examine 10) The drawing(s) filed on is/are: a) accompliant may not request that any objection to the Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the Examine 11) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of: 1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the priority documents 3. Acknowledgment is made of a claim for domesting application from the International Bureau * See the attached detailed Office action for a list 13) Acknowledgment is made of a claim for domesting action for domesting for domesting action for domesting action for domesting for domesting for domesting action for domesting for domestin	epted or b) objected to by the drawing(s) be held in abeyance. So ion is required if the drawing(s) is of caminer. Note the attached Office in priority under 35 U.S.C. § 119(s) have been received. In a particular, the shave been received in a polical rity documents have been received. In Indiana (PCT Rule 17.2(a)). In the certified copies not received.	ee 37 CFR 1.85(a). Dijected to. See 37 CFR 1.121(d). Ee Action or form PTO-152. Ea)-(d) or (f). Etion No Eed in this National Stage ed.				
since a specific reference was included in the first 37 CFR 1.78. a) The translation of the foreign language pro 14) Acknowledgment is made of a claim for domestic reference was included in the first sentence of the Attachment(s) 1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948)	exist sentence of the specification of existence of the specification of existence application has been recognitely under 35 U.S.C. §§ 120 se specification or in an Application of the existence of language of the existence of t	or in an Application Data Sheet. ceived. D and/or 121 since a specific				
Information Disclosure Statement(s) (PTO-1449) Paper No(s) I.S. Patent and Trademark Office	6)					

PTOL-326 (Rev. 11-03)

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DETAILED ACTION

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. Claims 1-16 are rejected under 35 U.S.C. 103(a) as being unpatentable over Mayer et al. (US 6,315,883; hereinafter "Mayer") in view of Shue et al. (US 6,083,835; hereinafter "Shue").

Mayer teaches a method for planarizing a non-planar conductive surface. A conducting material may be applied onto a top surface of the conductive surface layer using a method that does not involve electroplating so that a top surface of the conducting material layer is planar (especially, see col. 9, lines 37-39; 44-45), thus forming a planarized multi-layer structure that includes the non-planar conductive surface layer and the conducting material layer. The planarized multi-layer structure may be electropolished. At least portions of the non-planar top conductive layer may be removed along with portions of the conducting material layer (col.9-11; Figs. 4-7).

Mayer does not teach that the conducting material and the conductive surface layer may be electropolished at substantially the same rate. In a method of planarizing, Shue teaches that a layer of copper alloy may be deposited over the damascene wiring trench using any of several methods and then electropolished in order to prevent any

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dishing effects (col. 3, lines 26-38). Hence, it would have been obvious to one with ordinary skilled in the art to modify Mayer by using a layer of copper alloy as taught by Shue in order to prevent any dishing effects. Furthermore, because the combined Mayer and Shue has the conducting material that is similar to the material of the conductive surface layer, the electropolishing of both layers at substantially the same rate would have been expected.

Mayer teaches that the material may be further removed to expose a barrier layer and a dielectric layer (col. 10, lines 11-20; Fig. 8). Furthermore, it is a notoriously well-known practice in the damascene and metallization process in the semiconductor device fabrication.

As to dependent claims 10-14, Shue is not particular about forms of the material (e.g., slurry, power, or emulsion) and method for applying the conducting material. Hence, it would have been obvious to one with ordinary skilled in the art to use commercial available form of material (e.g., slurry, power, or emulsion) and method in order to accommodate various dimensions, shapes and product requirements. Thus, claims 10-14 are rejected for the same reason, supra.

As to dependent claims 15 and 16, the combined prior art teaches using electropolishing. The combined prior art is not particular about the process. Hence, it would have been obvious to one with ordinary skilled in the art to use ECME or electrochemical etching process because it is one of the most popular methods of electropolishing.

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The above-cited claims differ from the combined prior art by specifying well-known features (such as annealing process /diffusion process; removing layers using CMP, wet etching, or RIE) to the art of semiconductor device fabrication. A person having ordinary skill in the art would have found it obvious to modify the combined prior art by adding any of same well-known features to same in order to provide their art recognized advantages and produce an expected result. It is noted that applicant did not traverse the aforementioned conventionality (e.g., well-known features, obviousness), which have been stated in the previous office action on August 20, 2003.

Response to Arguments

3. Applicant's arguments filed November 25, 2003 have been fully considered but they are not persuasive.

Applicant has argued that Mayer does not show applying a conducting material layer onto a top surface of the conductive surface layer forming a planarized multi-layer structure. In fact, as has been stated in the office action, Mayer teaches applying a conducting material layer onto a top surface of the conductive surface layer forming a planarized multi-layer structure (especially, see col. 9, lines 37-39; 44-45).

Applicant has argued that the combined prior art does not teach annealing the conducting material layer. In response, as stated in the office action, annealing is a well-known process that has been used to eliminate stress and provide stable physical properties during the metallization process steps whenever needed.

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Applicant has argued that the combined prior art does not teach removing the material to expose a barrier layer and to expose a dielectric layer. In reply, as stated in the office action, Mayer teaches that the material may be further removed to expose a barrier layer and a dielectric layer (col. 10, lines 11-20; Fig. 8). Furthermore, it is a notoriously well-known practice in the damascene and metallization process in the semiconductor device fabrication.

Conclusion

4. THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

5. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Kin-Chan Chen whose telephone number is (571) 272-

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1461. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine Norton can be reached on (571) 272-1465. The fax phone number for the organization where this application or proceeding is assigned is (703) 872-9306. Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (571) 272-0988.

January 9, 2004

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